PATENT Docket No.: 2328-050A

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:	
Jian J. CHEN et al.	:	
U.S. Patent Application No	:	Group Art Unit:
Filed: Herewith	:	Examiner:

INDUCTIVE PLASMA PROCESSOR HAVING COIL WITH PLURAL WINDINGS AND For: METHOD OF CONTROLLING PLASMA DENSITY

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months after the U.S. filing date or before the mailing date of a first Office Action on the merits. No certification or fee is required.

The references were cited by or submitted to the U.S. Patent and Trademark Office in Parent Application No. 09/821,021, filed 03/30/2001, which is relied upon for an earlier filing date under 35 USC 120. Thus copies of these references are not attached. 37 CFR 1.98 (d).

Respectfully submitted,

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